IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Koichi KANAYA et al.

Application No.: New U.S. National Stage of PCT/JP2004/006007

Filed: January 24, 2006 Docket No.: 126247

For: VAPOR DEPOSITION APPARATUS AND VAPOR DEPOSITION METHOD

PRELIMINARY AMENDMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Please consider the following:

Amendments to the Claims as reflected in the listing of claims; and

Remarks.